

Substitute Form PTO-1449  
(Modified)U.S. Department of Commerce  
Patent and Trademark OfficeAttorney's Docket No.  
07977/226002/US3548D1Application No.  
09/596,755**Information Disclosure Statement  
by Applicant**

(Use several sheets if necessary)

(37 CFR §1.98(b))

JAN 10

Applicant  
Hisashi OhtaniFiling Date  
June 15, 2000Group Art Unit  
1765**U.S. Patent Documents**

Examiner Initial	Desig. ID	Patent Number	Issue Date	Patentee	Class	Subclass	Filing Date If Appropriate
J	AA	5,523,262	6/4/96	Fair, et al.			
	AB						
	AC						
	AD						
	AE						
	AF						
	AG						
	AH						
	AI						
	AJ						
	AK						

**Foreign Patent Documents or Published Foreign Patent Applications**

Examiner Initial	Desig. ID	Document Number	Publication Date	Country or Patent Office	Class	Subclass	Translation	
							Yes	No
	AL							
	AM							
	AN							
	AO							
	AP							

**Other Documents (include Author, Title, Date, and Place of Publication)**

Examiner Initial	Desig. ID	Document
J	AQ	Hirano, et al., "Low Temperature Activation method of Poly-Si films using Rapid Thermal Annealing", Vol. 3014, pgs. 119-126, Proceedings, February 1997.
	AR	
	AS	
	AT	

Examiner Signature

Patent Examiner

EXAMINER Initials citation considered. Draw line through citation if not in conformance and not considered. Include copy of this form with your communication to applicant.

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Examiner Initial	Desig. ID	Patent Number	Issue Date	Patentee	Class	Subclass	Filing Date If Appropriate
<i>1/2x</i>	AA	5,771,110	6/23/98	Hirano, et al.			
<i>1</i>	AB	5,837,568	11/17/98	Yoneda, et al.			
	AC						
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